



Form 1449 (Modified)	Atty Docket No. SRI1P036/US-4527-2	Application No.: 10/007,705
Information Disclosure Statement By Applicant	Applicant: Pelrine, et al.	
(Use Several Sheets if Necessary)	Filing Date 12/06/01	Group 2635

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
TMD	A1	5,977,685	11/02/99	Kurita, et al.			06/03/96
TMD	A2	6,048,622	04/11/00	Hagood IV, et al.			02/09/99
TMD	A3	6,060,811	05/09/00	Fox, et al.			07/25/97
TMD	A4	4,885,783	12/05/89	Whitehead, et al.			04/10/87
TMD	A5	4,843,275	06/27/89	Radice			01/19/88
TMD	A6	4,400,634	08/23/83	Micheron			12/09/80
TMD	A7	5,361,240	11/01/94	Pearce			07/10/90

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Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
TMD	B1	Ajluni, Cheryl, "Pressure Sensors Strive to Stay on Top, New Silicon Micromachining Techniques and Designs Promise Higher Performance", <i>Electronic Design - Advanced Technology Series</i> , October 3, 1994, pp. 67-74
TMD	B2	Ashley, S., "Smart Skis and Other Adaptive Structures", <i>Mechanical Engineering</i> , November 1995, pp. 77-81
Examiner: <i>Charmen M. Dougherty</i>		Date Considered: <i>May 14, 2004</i>

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Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
TMD	C1	Bar-Cohen, Yoseph, JPL, <i>WorldWide ElectroActive Polymers, EAP (Artificial Muscles) Newsletter</i> , Vol. 1, No. 1, June 1999.
TMD	C2	Cheng, Z.-Y., H. S. Xu, J. Su, Q. M. Zhjg, P.-C. Wang, and A. G. MacDiarmid, "High performance of all-polymer electrostrictive systems," <i>Proceedings of the SPIE International Symposium on Smart Structures and Materials: Electro-Active Polymer Actuators and Devices</i> , March 1-2, 1999, Newport Beach, California, USA., pp. 140-148.
TMD	C3	Kornbluh, R., Pelrine, R., Eckerl/e, J., Joseph, J., "Electrostrictive Polymer Artificial Muscle Actuators", <i>IEEE International Conference on Robotics and Automation</i> , Leuven, Belgium, 1998
TMD	C4	Ktech's PVDF Sensors, http://www.ktech.com/pvdf.htm , 06/06/2001, pp. 1-5.
TMD	C5	Pelrine, R., R. Kornbluh, and J. Joseph, FY 1998 <i>Final Report on Artificial Muscle for Small Robots</i> , ITAD-3482-FR-99-36, SRI International, Menlo Park, California, 1999
TMD	C6	Pelrine, R., R. Kornbluh, Q. Pei, and J. Joseph, "High Speed Electrically Actuated Elastomers with Over 100% Strain," <i>Science</i> , Vol. 287, No. 5454, pages 1-21, 2000
TMD	C7	Pelrine, R., R. Kornbluh, and G. Kofod, "High Strain Actuator Materials Based on Dielectric Elastomers," submitted to <i>Advanced Materials</i> (May 2000).
Examiner <i>Thomas M. Dougherty</i>	Date Considered <i>May 19, 2004</i>	

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TMD	D1	Pelrine, R., Roy Kornbluh, Jose Joseph, Qibing Pei, Seiki Chiba "Recent Progress in Artificial Muscle Micro Actuators," SRI International, Tokyo, 1999 MIT/NEEDOIMNIC, 1999
TMD	D2	Treloar, L.R.G, "Mechanics of Rubber Elasticity," <i>J Polymer Science, Polymer Symposium</i> , No. 48, pp. 107-123, 1974
TMD	D3	Uchino, K. 1986. "Electrostrictive Actuators: Materials and Applications," <i>Ceramic Bulletin</i> , 65(4), pp. 647-652, 1986
TMD	D5	Zhenyi, M., J.I. Scheinbeim, J.W. Lee, and B.A. Newman. 1994. "High Field Electrostrictive Response of Polymers," <i>Journal of Polymer Sciences, Part B-Polymer Physics</i> , Vol.32, pp. 2721-2731, 1994
TMD	D6	http://www.ph.unimelb.edu.au "The Rubbery Ruler", printed from web 7/25/01.
TMD	D7	Joseph, Jose, Ron Pelrine, Joe Eckerle, John Bashkin, and Prasanna Mulgaonkar, "Micro Electrochemical Composite Sensor, SRI International, printed from web 7/25/01.
TMD	D8	Pei, Qibing, Ron Pelrine, Roy Kornbluh, Sigridur Jonadottir, Venkat Shastri, Robert J. Full, "Multifunctional Electroelastomers: Electroactive Polymers Combining Structural, Actuating, and Sensing Functions" University of California at Berkeley, Berkeley, CA., available at www.sri.com-publications , January 17, 2001
TMD	D9	http:// www.neurosupplies.com/pdf_files/transducers.pdf , printed from web 7/25/01.
TMD	D10	PowerLab ADInstruments, "MLT001 High-Sensitivity Force Transducers, AD Instruments Transducers Series, printed from web 7/25/01.
TMD	D11	Julian W. Gardner, "Microsensors: Principles and Applications," John Wiley, 1994
Examiner: <i>Thomas M. Roughley</i>	Date Considered <i>May 14, 2004</i>	

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